

DUV scanning lithography machine

Nikon NSR-S204B

Machine introduction

ÿ Nikon NSR-S204B Scanning Lithography Machine

ÿ The wavelength of the light source is 248nm and the resolution is better than 0.18ÿm.

ÿ Mainly used in 4-inch, 6-inch and 8-inch production lines.

ÿ Widely used in MEMS/LED/compound (InP, APD)/RF/Mos.

More services

ÿ Provide Chinese and English software and 4", 6", 8" equipment silicon wafer modification.

ÿ All spare parts and consumables are provided all year round.

Resolution	0.18ÿm	Resolution	0.18ÿm
THAT	0.68	THAT	0.68
Exposure light source	248nm	Exposure light source	248nm
magnification	4:1	Magnification	4:1
Maximum exposure scene	25mm*33mm Maximum Exposure area 25mm*33mm		
Alignment accuracy LSA:40nm/FLA:45nm			